

After Etch Stress Relief in RT/duroid® High Frequency Laminates

As is typical of all polytetrafluoroethylene (PTFE) based circuit board materials in which the copper cladding is bonded to the dielectric at elevated temperatures, RT/duroid® laminates show some degree of dimensional shrinkage after copper is etched off. When the laminate is cooled to room temperatures after the copper has been bonded to the dielectric, the copper and dielectric are at different dimensions than they would be if not bonded together due to differences in the thermal coefficients of expansion (CTE's). The dielectric is trying to shrink but is restrained by the copper foil. Similarly the copper is trying to grow, but is restrained by the dielectric.

After lamination, 50% of the PTFE in the dielectric is in a crystalline phase, and 50% in the amorphous phase. The amorphous phase has both viscous and elastic properties; it is "viscoelastic." The elastic response to any applied stress is immediate; it will deform immediately. However the viscous response to the applied stress is time related; it will slowly deform over a period of time.

When a portion of the copper is etched away to generate the circuit, the internal stresses become unbalanced since there is now less copper trying to stretch the dielectric. There is an immediate elastic response by the crystalline portion of the PTFE, and the elastic response of the amorphous phase which results in a shrinking of the laminate. The viscous response of the amorphous phase results in a continued slow shrinking over time until a balance is reached. The shrinking due to the viscous response can take days.

To complicate the picture, the CTE's of the dielectric are different in the X- (Machine direction, MD) and Y- (Cross Machine Direction, CMD) axis for some of the laminates, so that the shrinkage can be different in the two axis. The amount of copper etched away, the distribution and geometry of the remaining copper, the relative thicknesses of the dielectric and copper, the type of copper, the type of dielectric, the amount of time elapsed since the material was laminated and the storage temperature, all affect the amount of the immediate and residual etch shrinkage in both the X- and Y- axis.

All of this makes it very difficult to predict the precise amount of etch shrinkage to expect. For many circuits the shrinkage is small enough to ignore, but for large circuits requiring close feature registration, the total material movement is large enough to create a problem. For cases where the shrinkage is not acceptable, a procedure called "double etching" is the solution. This process involves two separate image and etch steps, with a bake cycle between, to accelerate the residual shrinkage. This procedure eliminates approximately 90% of the etch shrinkage before the final circuit is etched. The remaining amount of movement will be typically no more than a few hundredths of a percent, which is small enough to ignore.

The double etch procedure consists on generating two sets of artwork: a "rough" and a "final." The rough artwork exposes about 90% of the copper to be etched away, leaving copper only in the areas where the final circuit will be. It can be conveniently created by increasing the final line widths and lengths by 10% to 15%. The circuit board is imaged with the rough artwork and the exposed copper etched off. It should be noted that any tooling holes or targets will move as the material shrinks after etching, and will be useless for further locating. Consequently new holes or targets will need to be added before the final etch. The final artwork can be registered to the board by including narrow lines in the rough artwork in the X- and Y- axis, crossing close to the board center.

Before the final artwork can be imaged, the residual etch shrinkage needs to be eliminated. Since this is a time related property, we could wait until the strain relief occurred. However, this could take many days before the amount of residual shrinkage was reduced to ignorable levels. The amorphous phase of PTFE is characterized by a glassy state and a rubbery state, and strain relief occurs at a much faster rate in the rubbery than in the glassy state. The glass transition temperature is about 130°C (266°F), so that the rate of strain relief can be accelerated by baking the circuit board above 130°C (266°F). Experimental data indicates that no significant material shrinkage can be detected after a 2 hour 225°C bake in a nitrogen purged oven. The presence of oxygen at this time/temperature exposure will cause oxidation of the copper and lead to

reduced copper peel strength. An alternative to nitrogen purge ovens is the use of hot air recirculating ovens with a modified bake cycle that would not alter the copper peel strength. This modified cycle only eliminates about 60% of the etch shrinkage. The cycle depends on the kind of material as presented in Table I. During the bake cycle, the circuit panels need to be free of constraints so as to allow free movement of the material. An after bake stabilization period of 10 hours is needed on RT/duroid 5880 and 5870 materials to allow for final stress relief. The photomask from the rough etching should be removed before the bake cycle.

The boards are now stabilized and very little further etch shrinkage is expected. Table II presents dimensional change of RT/duroid laminates after all copper has been etched off, the total movement for a given circuit is proportional to the amount of copper left on the board. The final artwork is aligned to the centerlines from the rough artwork, and tooling holes punched or drilled. If plated through holes are needed, these can now be drilled, sodium etched, and all surfaces electroless plated. A reverse photomask exposing the surfaces to be plated is imaged, and the board plated to the desired thickness. Solder or gold is now plated onto the exposed copper, and finally the remaining copper (including the exposed electroless deposition) is etched away, using the solder or gold as an etch mask. If there are no plated through holes, or as an alternative process, a positive final artwork can be imaged and the remaining copper etched after punching or drilling the tooling holes.

This two-step etching and baking cycle will result in very small dimensional changes in the final circuit. Tight dimensional tolerances with excellent feature registration can be achieved, allowing one to obtain the maximum performance from RT/duroid laminates.

Table I. Stress Relieving Bake Cycles

RT/duroid Laminate	Recommended Bake Cycle	Alternative Bake Cycle	Stabilization
5870	2 hours @ 225°C	1 hour @ 175° C	10 hours
5880	2 hours @ 225°C	1 hour @ 175° C	10 hours
6006	2 hours @ 225°C	2 hours @ 150° C	not needed
6010	2 hours @ 225°C	2 hours @ 150° C	not needed

Table II. Typical Dimensional Change of RT/duroid Laminates

RT/duroid Material Grade and Thickness		Recommended Bake Cycle CMD%		Alternative Bake Cycle CMD% MD%	
5880	0.010"	-0.557	-0.155	-0.411	-0.085
5880	0.062"	-0.350	-0.112	-0.277	-0.079
5870	0.010"	-0.178	-0.025	-0.144	+0.005
5870	0.062"	-0.093	-0.006	-0.061	+0.078
6006	0.010"	-0.877	-1.089	-0.641	-0.807
6010	0.010"	-0.320	-0.330	-0.209	-0.209
6010	0.050"	-0.330	-0.339	-0.211	-0.221

Note: RT/duroid 6002 laminates and TMM[®] Temperature Stable Laminates have minimal etch shrinkage since their CTE's were engineered to be the same as that of copper (16 ppm/°C) for the X- and Y- axis. Typical values are 0.02% or less of shrinkage. This very low number allows tight after etch registration without the need of a double etch procedure.

The information contained in this fabrication note is intended to assist you in fabricating Rogers' laminates. It is not intended to and does not create any warranties, express or implied, including any warranty of merchantability or fitness for a particular application. The user should determine the suitability of Rogers' circuit materials for each application.

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Revised 1660 082423 **Publication #92-422**